

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:

Narwankar et al.

Application No.: 10/772,893

Filed: February 4, 2004

For: TAILORING NITROGEN PROFILE  
IN SILICON OXYNITRIDE USING  
RAPID THERMAL ANNEALING WITH  
AMMONIA UNDER ULTRA-LOW  
PRESSURE

Examiner: Kelly M Stouffer

Art Unit: 1792

Confirmation No.: 5371

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT UNDER 37 CFR §1.111**

Dear Examiner:

This is in response to the Office Action mailed June 17, 2008. Applicants respectfully request the Examiner to enter this Amendment and consider the following remarks.

**The Listing of Claims** begins on page 2 of this paper.

**Remarks/Arguments** begin on page 11 of this paper.

I hereby certify that this correspondence is being deposited via  
EFS Web on the date below:

September 17, 2008

Date of Deposit

/Justin K. Brask/

Justin K. Brask, Reg. #61,080